



PATENT APPLICATION

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Attorney Docket No.: 2437.09US04

HIATT et al.

Confirmation No.: 2768

Application No.: 10/077,180

Filed: February 15, 2002

For: ULTRA-MINIATURE MAGNETIC DEVICE

Group Art Unit: 3729

INFORMATION DISCLOSURE STATEMENT

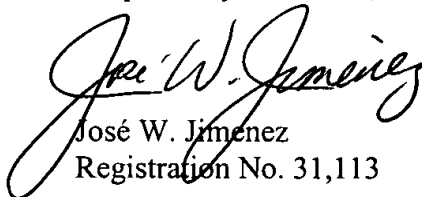
Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Pursuant to 37 C.F.R. § 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached Form PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This information is being filed before the mailing date of a first Office Action on the merits. No certification or fee is required.

Respectfully submitted,

  
José W. Jiménez  
Registration No. 31,113

Customer No. 24113  
Patterson, Thunte, Skaar & Christensen, P.A.  
4800 IDS Center, 80 South 8th Street  
Minneapolis, Minnesota 55402-2100  
Telephone: (612) 349-5743

RECEIVED  
AUG - 7 2002  
TC 3700 MAIL ROOM

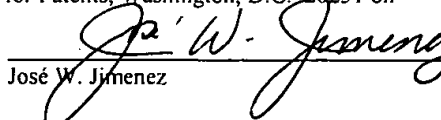
*Please grant any extension of time necessary for entry; charge any fee due to Deposit Account No. 16-0631.*

CERTIFICATE OF MAILING

I hereby certify that this document is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on

Date of Deposit

8/1/02

  
José W. Jiménez

[illegible]

[illegible]



FORM PTO-1449 MODIFIED		Docket No.: 2437.09US04	Application No.: 10/077,180
<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>		APPLICANT: HIATT et al.	
		FILING DATE: February 15, 2002	
		GROUP ART UNIT: 3729	
<b>OTHER DOCUMENTS</b>			
Examiner Initials	(Author, Title, Date, Pertinent Pages, etc.)		
	Park et al., "High Current Integrated Microinductors and Microtransformers using Low Temperature Fabrication Processes," <i>SPIE Proceedings</i> Vol. 2920, 1996 International Symposium on Microelectronics, Minneapolis, Minnesota, USA, October 1996.		
	Park et al., "A Comparison of Micromachined Inductors with Different Magnetic Core Materials," <i>IEEE 46<sup>th</sup> Electronic Components &amp; Technology Conference</i> , Orlando, FL, pp. 375-381, 1996.		
	Ahn et al., "A Planar Micromachined Spiral Inductor for Integrated Magnetic Microactuator Applications," <i>J. Micromech. Microeng.</i> , Volume 3, pp. 37-44, 1993.		
	Ahn et al., "A Planar Variable Reluctance Magnetic Micromotor with Fully Integrated Stator and Coils," <i>Journal of Microelectromechanical Systems</i> , Volume 2, No. 4, pp. 165-173, December 1993.		
	Ahn et al., "A New Toroidal-Meander Type Integrated Inductor with a Multilevel Meander Magnetic Core," <i>IEEE Transactions on Magnetics</i> , Volume 30, No. 1, pp. 73-79, January 1994.		
	Ahn et al., "A Fully Integrated Planar Toroidal Inductor with a Micromachined Nickel - Iron Magnetic Bar," <i>IEEE Transactions on Components, Packaging, and Manufacturing Technology</i> , Part A., Volume 17, No. 3, pp. 463-469, September 1994.		
	Ahn et al., "A Fully Integrated Surface Micromachined Magnetic Microactuator with a Multilevel Meander Magnetic Core," <i>Journal of Microelectromechanical Systems</i> , Volume 2, No. 1, pp. 15-22, March 1993.		
	Mino et al., "Planar Microtransformer with Monolithically-Integrated Rectifier Diodes for Micro-Switching Converters," <i>IEEE Transactions on Magnetics</i> , Volume 32, No. 2, pp. 291-296.		
	Hayano et al., "Development of Film Transformer," <i>IEEE Transactions on Magnetics</i> , Volume 30, No. 6, pp. 4758-4760, November 1994.		
	Yamaguchi et al., "Characteristics of a Thin Film Microtransformer with Circular Spiral Coils," <i>IEEE Transactions on Magnetics</i> , Volume 29, No. 5, pp. 2232-2236, September 1994.		
	Yamaguchi et al., "Characteristics of a DC-DC Converter Using a Thin Film Microtransformer and a Microinductor," <i>IEEE Transactions Journal on Magnetics in Japan</i> , Volume 9, No. 6, pp. 84-89, November/December 1994.		
	Yachi et al., "Thin Film Transformer Fabricated by a Dry Process," <i>NTT Review</i> , Volume 4, No. 3, pp. 46-50, May 1992.		
	Frazier et al., "Development of Micromachined Devices Using Polyimide-Based Processes," <i>Sensors and Actuators A</i> 45, pp. 47-55, 1994.		
EXAMINER SIGNATURE	DATE CONSIDERED		
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.			

RECEIVED  
AUG-7 2002  
TC 370 MAIL ROOM